

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 106200.01		APPLICATION NO. Rule 53(b) Continuing Application of U.S. Application No. 09/571,864 Filed May 16, 2000	
INFORMATION DISCLOSURE STATEMENT		(Use several sheets if necessary)		APPLICANTS Satoshi TATSUURA, Yasuhiro SATO, Minquan TIAN, and Lyong Sun PU		FILING DATE February 26, 2002	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME		CLASS	SUB CLASS
<i>AS</i>		4,349,583	09/1982	KULYNYCH et al.		<i>427</i>	<i>53.1</i>
<i>AS</i>		4,217,183	08/1980	MELCHER et al.		<i>204</i>	<i>15</i>
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY		CLASS	SUB CLASS
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
<i>AS</i>		Gutfeld et al., <u>Electrochemical microfabrication by laser-enhanced photothermal processes</u> , IBM J. Res. Develop., Vol. 42, No. 5, 1998, pp. 639-652. <i>no month</i>					
<i>AS</i>		Chichkov et al., <u>Femtosecond, picosecond and nanosecond laser ablation of solids</u> , Applied Physics A, 63, 1996, pp. 109-115. <i>no month</i>					
<i>AS</i>		Obara et al., <u>Laser Engineering Optics</u> , Kyoritsu Shuppan, 1998, pp. 130-133. <i>no month</i>					
<i>AS</i>		GUTFELD et al., "Electrochemical Microfabrication by Laser-Enhanced Photothermal Processes," J. Res. Develop., Vol. 42, No. 5, pp. 639-652, September 1998.					
EXAMINER		<i>Edna Wong</i>				DATE CONSIDERED <i>1/22/04</i>	
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							